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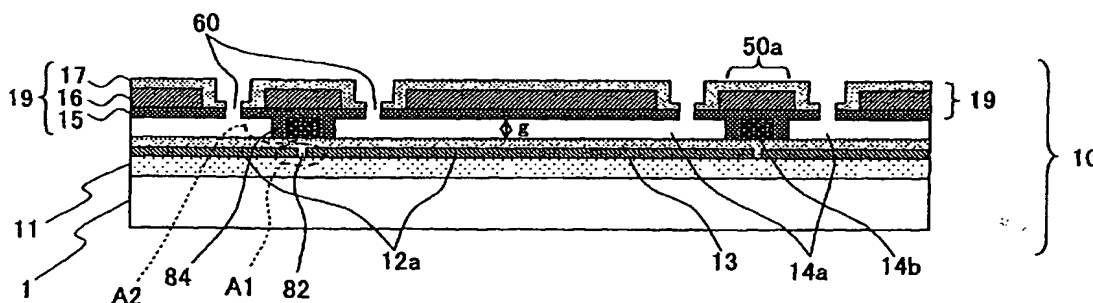
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(54) Title: ELECTROSTATIC ACTUATOR FORMED BY A SEMICONDUCTOR MANUFACTURING PROCESS



(57) **Abstract:** An electrostatic actuator has high-reliability and less variation in characteristics. An electrode (12a) is formed on a substrate (1), and a plurality of partition parts (50a) are formed on the electrode. A vibration plate (19) is formed on the partition parts (50a), and is deformable by an electrostatic force generated by a voltage applied to the electrode (12a) so that an air gap (14a) is formed between the partition parts (50a) by etching a part of a sacrifice layer (14) formed between the electrode (12a) and the vibration plate (19). The partition parts (50a) are formed of remaining parts of the sacrifice layer (14) after the etching.